



PATENT  
8565D-7213 (81839.0077)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Teruaki FUKAMI

Serial No: 09/218,997

Filed: December 22, 1998

For: SILICON WAFER STORAGE WATER AND  
SILICON WAFER STORAGE METHOD

Art Unit: 1744

Examiner: I. Soubra

20/C  
AS

I hereby certify that this correspondence  
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Name

John P. Scherlacher 03/27/02

Signature

Date

AMENDMENT

Box Non-Fee Amendment  
Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

In response to the Office Action dated December 31, 2001, please amend the  
above-identified application as follows:

IN THE CLAIMS:

Cancel claims 7 and 9, without prejudice.

RECEIVED

APR 9 - 2002

IC 1700